

The invention relates to electronics, in particular to the technology of manufacturing materials used in electronics and instrument engineering, namely to the ordered compo-site nanostructures.

The method of manufacturing the filamentary nanostructure includes the manufacture of a workpiece blank by assembling a bundle of microwire segments each in glass insulation, placement of bundle inside a glass ampoule, vacuumization and sealing thereof and compression of bundle by heating to the ampoule walls softening temperature, thinning of the workpiece blank by its pulling up to the obtaining of the filamentary nanostructure with nanowires at a temperature above the temperature of softening of all glass components and of melting of microwires in the working filamentary nanostructure formation zone, and its subsequent cooling. Thinning of the workpiece blank is performed by consecutive pulling thereof in several cycles, at the same time its pulling during one cycle is carried out under the action of a constant force and a constant temperature, so that the ratio of this force to the viscosity of the glass at the bottom of the workpiece blank working heating zone may stepwise decrease from cycle to cycle proportional to the decrease of the pulled workpiece blank diameter square.

Claims: 4

Fig.: 4